

- [11] 2016/11/16@Hamamatsu in Japan
The 16th International Conference on Precision Engineering (ICPE2016)
Investigation of determining factor of etching rate of single crystal diamond in plasma chemical vaporization machining
○H. Dojo, K. Endo, H. Yamada, A. Chayahara, Y. Mokuno, K. Yamamura

- [10] 2016/11/16@Hamamatsu in Japan
The 16th International Conference on Precision Engineering (ICPE2016)
Highly-efficient pit-free and slurryless finishing of GaN by plasma-assisted polishing
○C. Kageyama, H. Deng, K. Endo, K. Yamamura

- [09] 2016/11/15@Hamamatsu in Japan
The 16th International Conference on Precision Engineering (ICPE2016)
Precise correction of cylindrical shape by numerically controlled plasma chemical vaporization machining
○Y. Goto, Y. Kobayashi, K. Endo, D. Yamazaki, R. Maruyama, H. Hayashida, K. Soyama, K. Yamamura

- [08] 2016/11/15@Hamamatsu in Japan
The 16th International Conference on Precision Engineering (ICPE2016)
High-efficiency and high-precision flatness correction of quartz glass substrate by numerically controlled vacuum plasma chemical vaporization machining
○S. Sakaiya, D. Funato, K. Endo, K. Yamamura

- [07] 2016/09/13@Garmisch-Partenkirchen in Germany
15th International Conference on Plasma Surface Engineering
Surface modification of polytetrafluoroethylene (PTFE) by heat-assisted atmospheric pressure plasma treatment for improving adhesion between PTFE and isobutylene-isoprene rubber (IIR)
○Y. Ohkubo, K. Ishihara, M. Shibahara, A. Nagatani, K. Honda, T. Aoki, Y. Kodama, K. Endo, and K. Yamamura

- [06] 2016/08/29@San Diego in USA
SPIE Optics + Photonics 2016, Advances in Metrology for X-Ray and EUV Optics VI
Measurement of aspheric mirror by nanoprofiler using normal vector tracing
○T. Kitayama, H. Shiraji, K. Yamamura, K. Endo

- [05] 2016/06/01@Nottingham in UK
16th International Conference of the European Society for Precision Engineering and Nanotechnology
Highly-efficient slurryless finishing of GaN by plasma-assisted polishing using a resin bonded grinding stone
○C. Kageyama, H. Deng, K. Endo, K. Yamamura

- [04] 2016/06/01@Nottingham in UK
16th International Conference of the European Society for Precision Engineering and Nanotechnology
Electrochemical mechanical polishing of difficult-to-machine mold materials
OK. Yamamura, Y. Imanishi, K. Endo

- [03] 2016/06/01@Nottingham in UK
16th International Conference of the European Society for Precision Engineering and Nanotechnology
Planarization of CVD grown single crystal diamond wafer by numerically controlled plasma chemical vaporization machining
OH. Dojo, K. Endo, H. Yamada, A. Chayahara, Y. Mokuno, K. Yamamura

- [02] 2016/05/20@Yokohama in Japan
International Conference on X-ray Optics, Detectors, Sources, and their Applications 2016
3D surface measurement of spherical mirror by nanoprofiler using normal vector tracing method
OH. Shiraji, Y. Tokuta, T. Kitayama, M. Nakano, R. Kudo, K. Yamamura, K. Endo

- [01] 2016/04/20@Tokyo in Japan
18th CIRP Conference on Electro Physical and Chemical Machining (ISEM XVIII)
High-spatial Resolution Figuring by Pulse Width Modulation Controlled Plasma Chemical Vaporization Machining
OK. Yamamura, Y. Takeda, S. Sakaiya, D. Funato, K. Endo